

**saes**  
group

# SAES Pure Gas

*The Technology of Pure Gas*

## AMBIENT INLINE PURIFIER 502 PURIFICATION MEDIA SPECIFICATION



**0 – 125 slpm Ambient Inline Purifiers.  
For consistent gas quality and  
Impurity removal to pptV levels.**

### MicroTorr Ambient Inline Purifiers:

MicroTorr purifiers are the most complete and reliable solution for Point-of-Use (POU) gas purification. Combining model size with a selection of gas-specific purification materials, MicroTorr purifiers can be tailored to many different customer applications, while maintaining impurity removal to Part-Per-Billion (ppbV) levels or better. Optional valves and a 0.003 micron particle filter are available as well as custom subsystem configurations.

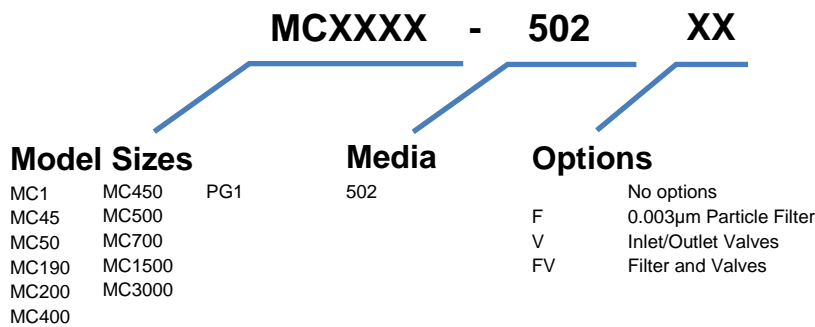
### Competitive Advantages and Benefits:

- **Reliability:** Uncompromised process consistency and yield improvement.
- **Performance:** State-of-the-art purification technology, low pressure drop, and long lifetimes.
- **Regenerability:** Most MicroTorr media are factory regenerable, minimizing potentially hazardous waste.
- **Quality:** 316L stainless steel, Helium leak checked, and analytical testing to part-per-trillion (pptv) levels.
- **Support:** Lifetime estimation and regeneration service available through SAES Pure Gas Sales Network.

### 502 Media Purifier Properties

<b>Gases Purified</b>	AsH <sub>3</sub> , PH <sub>3</sub>
<b>Impurities Removed</b>	H <sub>2</sub> O, O <sub>2</sub> to < 1 ppb, Metals < 1 ppbV
Particle Filtration	2 micron or 0.003 micron metal
Vessel construction	Stainless Steel 316L, electropolished to 10 Ra
Installation Orientation	Vertically with flow downward. Consult factory for other orientations.
Leak Rating	1 x 10 <sup>-9</sup> atm cc/sec of He
Operating temperature	-20 to 40 °C (-4 to 104°F)
Lifetime	Contact SAES Pure Gas for application specific lifetime calculations
Regenerability	Not Regenerable
Certification	CE Certified to the Pressure Equipment Directive (PED) Designed in accordance with ASME

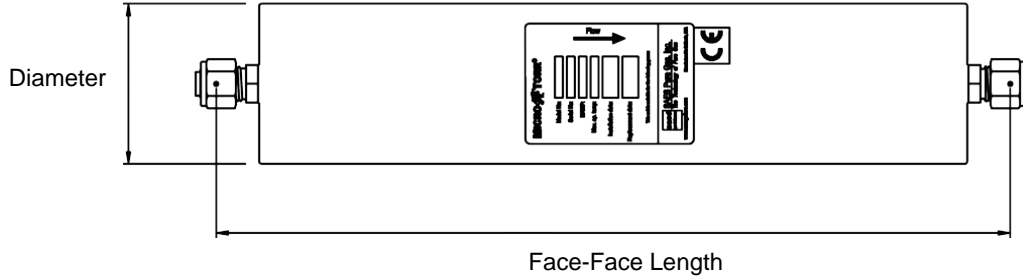
### Part Number Configuration:



### Purifier Sizes

Part Number	Maximum Flow (slpm)	Average Flow (slpm)	Operating Pressure (psig) Must be in gas phase	Inlet Connection	Outlet Connection	Diameter (inches [mm])	Face to Face Length (inches [mm])	Weight (lb. [kg])
<b>Standard Models</b>								
MC1-502F	1	0.8	1,000	1/4" MVCR	1/4" MVCR	1.5 [38.1]	3.31 [84.1]	< 0.7 [0.3]
MC45-502 MC45-502F	4	2	1,000	1/4" MVCR	1/4" MVCR	1.5 [38.1]	4.50 [114.3]	< 0.9 [0.4]
MC50-502F	4	2	1,000	1/4" MVCR	1/4" MVCR	1.5 [38.1]	5.00 [127.0]	< 0.9 [0.4]
MC190-502F	14	7	250	1/4" MVCR	1/4" MVCR	2.0 [50.8]	8.20 [208.3]	< 1.6 [0.7]
MC200-502F	10	5	250	1/4" MVCR	1/4" MVCR	2.0 [50.8]	6.30 [160.0]	< 1.8 [0.8]
MC400-502F	32	15	250	1/4" MVCR	1/4" MVCR	3.0 [76.2]	8.20 [208.3]	< 4.9 [2.2]
MC450-502F	28	10	250	1/4" MVCR	1/4" MVCR	3.0 [76.2]	7.94 [201.7]	< 4.1 [1.8]
MC500-502F	20	12	250	1/4" MVCR	1/4" MVCR	2.0 [50.8]	12.50 [317.5]	< 2.8 [1.2]
MC700-502F	45	37	250	1/4" MVCR	1/4" MVCR	3.0 [76.2]	10.00 [254.0]	< 7.6 [3.4]
MC1500-502F	70	40	250	1/2" MVCR	1/2" MVCR	3.0 [76.2]	18.20 [462.3]	< 8.0 [3.6]
MC3000-502 MC3000-502F	125	80	250	1/2" MVCR	1/2" MVCR	4.0 [101.6]	20.00 [508.0]	< 14.0 [6.4]

F = 0.003 micron particle filter



**Purifier Sizes, with inlet and outlet isolation valves**

Part Number	Maximum Flow (slpm)	Average Flow (slpm)	Operating Pressure (psig) Must be in gas phase	Inlet Connection	Outlet Connection	Diameter (inches [mm])	Face to Face Length with valves (inches [mm])	Weight with valves (lb. [kg])
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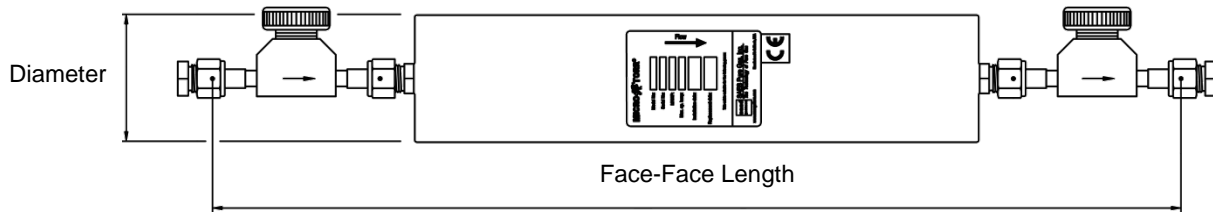
**Standard Models**

MC1-502FV	1	0.8	1,000	1/4" FVCR	1/4" FVCR	1.5 [38.1]	8.91 [226.3]	< 2.6 [1.2]
MC45-502V MC45-502FV	4	2	1,000	1/4" FVCR	1/4" FVCR	1.5 [38.1]	10.10 [256.5]	< 2.9 [1.3]
MC50-502FV	4	2	1,000	1/4" FVCR	1/4" FVCR	1.5 [38.1]	10.60 [269.2]	< 2.9 [1.3]
MC190-502FV	14	7	250	1/4" FVCR	1/4" FVCR	2.0 [50.8]	13.80 [350.5]	< 3.7 [1.7]
MC200-502FV	10	5	250	1/4" FVCR	1/4" FVCR	2.0 [50.8]	11.90 [302.3]	< 3.8 [1.8]
MC400-502FV	32	15	250	1/4" FVCR	1/4" FVCR	3.0 [76.2]	13.80 [350.5]	< 6.8 [3.1]
MC450-502FV	28	10	250	1/4" FVCR	1/4" FVCR	3.0 [76.2]	13.54 [343.9]	< 6.0 [2.7]
MC500-502FV	20	12	250	1/4" FVCR	1/4" FVCR	2.0 [50.8]	18.10 [459.7]	< 4.5 [2.0]
MC700-502FV	45	37	250	1/4" FVCR	1/4" FVCR	3.0 [76.2]	15.60 [396.2]	< 9.6 [4.4]
MC1500-502FV	70	40	250	1/2" FVCR	1/2" FVCR	3.0 [76.2]	28.84 [732.5]	< 12.5 [5.8]
MC3000-502V MC3000-502FV	125	80	250	1/2" FVCR	1/2" FVCR	4.0 [101.6]	30.64 [778.3]	< 18.7 [8.5]

**“U” Shaped Manifold**

PG1-502FV	14	7	250	1/4" FVCR	1/4" MVCR	2.0 [50.8]	13.80 [350.5]	< 5.1 [2.3]
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F = 0.003 micron particle filter  
V = inlet and outlet isolation valves



**Bypass and Dual Purifier Manifold Assemblies:**

Many configurations are available; please consult the factory for details.

**Other Purification Media's Available:**

Media	Gases Purified	Impurities Removed
202	CDA, O2, N2, Ar, He, Kr, Ne, Xe, H2, D2, CO2, N2O, NO, CF4	H2O to < 1 ppb
203	CDA, O2, N2, Ar, He, Kr, Ne, Xe, H2, D2, N2O, NO, CF4	H2O, CO2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppb
302	HCl, Cl2, B2H6, BCl3, CClH3, GeCl4, GeH4, H2S, H2Se, HBr, NF3, SiCl4, SiF4, SiH2Cl2, SiHCl3, SO2, CHClF2, BF3,	H2O to < 1 ppb; Metals < 1 ppb
403	N2, Ar, He, Kr, Ne, Xe, H2, CDA, O2	Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppb
404	N2, Ar, He, Kr, Ne, Xe, H2, CDA, O2, CO2, C2H2, C3H6, C2H4, NH3, C2H6, C3H8, C4H10	Organics < 1 pptV, Metals < 1 ppbV
<b>502 Covered by this Specification</b>	<b>AsH3, PH3</b>	<b>H2O, O2 to &lt; 1 ppb, Metals &lt; 1 ppbV</b>
503	H2 with up to 1% O2; O2 with up to 2% H2	H2 in O2 or O2 in H2 < 1 ppmV
602	CO	H2O, O2, CO2, Acids, Bases, Organics, Refractory Compounds, Metals < 1 ppbV
702	NH3, C2H7N, C2H8N2, C2H4, C3H6, CH3SiH3, GeH4, SF6, SiH4, H2/SiH4 mixtures	H2O, O2, CO2, NMHCs, Metals to < 1 ppb
802	SiH4	H2O, O2, CO, CO2, NMHCs, Sulphur compounds, Metals removal < 1 ppb
804	CO2	H2O, O2, CO, H2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV
805	CO2	H2O < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV
902	N2, Ar, He, Kr, Ne, Xe, CH4, C2H6, C3H8, C4H10, SF6, Fluorocarbons	H2O, O2, CO, CO2, H2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV
904	H2, D2, H2-Inerts Mix	H2O, O2, CO, CO2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV
906	CDA, O2, N2O	H2O, CO, CO2, NMHC to < 1 ppb, Metals < 1 ppbV

**Purifier Regeneration:**

Available from any SAES Pure Gas Regeneration Center.



**CE Directive:**

All MicroTorr Purifiers meet CE directive requirements and come with the CE Marking.

